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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Priority Application Serial No. 09/457,206
Priority Filing Date 12/7/99
Inventor G.S. Sandhu et al.
Assignee Micron Technology, Inc.
Priority Group Art Unit 2812
Priority Examiner Richard A. Booth
Attorney's Docket No. MI22-1685
Title: Method of Forming a Thin Film Transistor

PRELIMINARY AMENDMENT

To: Box Patent Application
Assistant Commissioner for Patents
Washington, D.C. 20231

From: David G. Latwesen, Ph.D. (Tel. 509-624-4276; Fax 509-838-3424)
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AMENDMENTS

In the Specification

At p. 1, before the "Technical Field" section insert:

-- RELATED PATENT DATA

*A
SUB*

This patent is a continuation application of U.S. Patent Application Serial No. 09/457,206 which was filed on December 7, 1999, which is a continuation of U.S. Patent No. 6,001,675, issued on December 14, 1999, which is a continuation of U.S. Patent No. 5,665,611, which was issued on September 9, 1997--.